



IFW

PATENT  
Customer No. 22,852  
Attorney Docket No. 3180.0342

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)	
	)	
NOBUHIRO KOMINE	)	
	)	
Application No.: 10/721,903	)	Group Art Unit: 2851
	)	
Filed: November 26, 2003	)	Examiner: D. Rutledge
	)	
For: RETICLE, EXPOSURE	)	Confirmation No.: 9102
MONITORING METHOD,	)	
EXPOSURE METHOD AND	)	
MANUFACTURING METHOD	)	
FOR SEMICONDUCTOR DEVICE	)	

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**AMENDMENT**

In reply to the Office Action mailed November 16, 2005, the period for response to which extends through February 16, 2006, please amended the above-captioned application, as follows:

**Amendments to the Claims** are reflected in the listing of claims in this paper.

**Remarks/Arguments** follow the amendment section of this paper.